

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants : Yasuo KOBAYASHI, et al. **Confirmation No.: 7185**  
U.S. Serial No. : 10/549,859  
Filed : June 6, 2006  
Examiner : Michael G. Miller  
Group Art Unit : 1792  
For : PLASMA-ASSISTED DEPOSITION METHOD AND PLASMA-  
ASSISTED DEPOSITION SYSTEM

**AMENDMENT PURSUANT TO RULE 111**

**MAILSTOP: AMDT**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed February 23, 2010, to which a response was due May 23, 2010, please consider the amendments and remarks as set forth below. A Petition for a Third Month Extension of Time, together with the requisite fee, is enclosed to extend the response due date to August 23, 2010.

Amendments to the Claims begin on page 2.

Remarks begin on page 5.